

FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)  October 17, 2003				ATTY DOCKET NO. 00684.00152.13		APPLICATION NO. Divisional of Appln. No. 09/819,488, filed March 19, 2001	
				APPLICANT Akiyoshi SUZUKI et al.			
				FILING DATE October 17, 2003		GROUP 2852	

  

U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
JFB	US-3,729,252	04/24/1973	Nelson	350	162 SF		
JFB	US-3,776,633	12/04/1973	Frosch et al.	355	132		
JFB	US-3,887,816	06/03/1975	Colley	350	571		
JFB	US-4,497,015	01/29/1985	Konno et al.	362	268		
JFB	US-4,498,742	02/12/1985	Uehara	350	523		
JFB	US-4,521,082	06/04/1985	Suzuki et al.	350	405		
JFB	US-4,619,508	10/28/1986	Shibuya et al.	353	122		
JFB	US-4,634,240	01/06/1987	Suzuki et al.	350	508		

  

FOREIGN PATENT DOCUMENTS							
DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT		
JFB 61-91662	05/09/1986	Japan	<del>—</del>	<del>—</del>	Abstract		
JFB 0 346 844	06/13/1989	Europe	<del>—</del>	<del>—</del>			
JFB 0 293 643	05/10/1988	Europe	<del>—</del>	<del>—</del>			
JFB 0 437 376	01/11/1991	Europe	<del>—</del>	<del>—</del>			
JFB 0 486 316	11/15/1991	Europe	<del>—</del>	<del>—</del>			

  

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)	
JFB	Pol, Victor, et al. "Excimer Laser Based Lithography: A Deep-Ultraviolet Wafer Stepper for VLSI Processing," <u>Optical Engineering</u> , Vol. 26, No. 4, pp. 311-318, April 1987.
JFB	Yang, S.T., et al. "Effect of Central Obscuration on Image Formation in Projection Lithography," <u>SPIE Vol. 1264 Optical/Laser Microlithography III</u> , pp. 477-485, 1990.
JFB	H cht-Zajac, <u>Optics</u> , 1 <sup>st</sup> Edition, p. 117, 1974.

  

EXAMINER  <i>Fred F Brown</i>	DATE CONSIDERED  <i>April 27, 2004</i>
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JFB		US-4,645,924	02/24/1987	Suzuki et al.	250	236	
JFB		US-4,668,077	05/26/1987	Tanaka	355	30	
JFB		US-4,780,747	10/25/1988	Suzuki et al.	355	68	
JFB		US-4,851,882	07/25/1989	Takahashi et al.	355	46	
JFB		US-4,924,257	05/08/1990	Jain	355	53	
JFB		US-4,931,830	06/05/1990	Suwa et al.	355	71	
JFB		US-4,947,030	08/07/1990	Takahashi	250	201.1	
JFB		US-4,988,188	01/29/1991	Ohta	353	122	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
JFB		39 33 308 A1	05/03/1990	Germany	—	—	No
JFB		28 35 363 A1	03/13/1980	Germany	—	—	No
JFB		40 07 069 A1	09/20/1990	Germany	—	—	No
JFB		61-210627	09/18/1986	Japan	—	—	Abstract
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
JFB		Intl. Cl., 5 <sup>th</sup> Edition, Vol. 7, Section G, pp. 68 and 72, 1989.					
JFB		Glatzel, Erhard. "New Lenses for Microlithography," SPIE, Vol. 237, p. 310, International Lens Design Conference (OSA), 1980.					
JFB		European Search Report regarding 01200962.7 dated May 31, 2001.					
JFB		European Search Report regarding 97200014.5 dated May 20, 1997.					
EXAMINER  <i>Fred S Brown</i>				DATE CONSIDERED  <i>April 2, 2004</i>			

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FSB		US-5,061,956	10/29/1991	Takubo et al.	355	55	
FSB		US-5,119,390	06/02/1992	Ohmori	372	25	
FSB		US-5,144,362	09/01/1992	Kamon et al.	355	53	
FSB		US-5,153,419	10/06/1992	Takahashi	250	201.1	
FSB		US-5,160,962	11/03/1992	Miura et al.	355	53	
FSB		US-5,237,367	08/17/1993	Kudo	355	67	
FSB		US-5,245,384	09/14/1993	Mori	355	67	
FSB		US-5,251,067	10/05/1993	Kamon	359	628	
FSB		US-5,253,040	10/12/1993	Kamon et al.	356	399	
FSB		US-5,264,898	11/23/1993	Kamon et al.	355	67	
FSB		US-5,286,963	02/15/1994	Torigoe	250	201.2	
FSB		US-5,287,142	02/15/1994	Kamon	355	53	
FSB		US-5,296,892	03/22/1994	Mori	355	67	
FSB		US-5,357,311	10/18/1994	Shiraishi	355	53	
FSB		US-6,271,909	08/07/2001	Suzuki et al.	355	53	
FSB		US-4,988,188	01/29/1991	Ohta	353	122	
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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
		Affidavit of Carl Zeiss in the opposition to EP 0 183 827 by Canon KK, 1994					
EXAMINER  Gret S Brown				DATE CONSIDERED  April 2, 2004			

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